



AF / IFW

Docket No.: 50432-601

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:	Customer Number: 20277
Minh Van NGO, et al.	:	Confirmation Number: 3500
Application No.: 10/617,451	:	Group Art Unit: 2812
Filed: July 11, 2003	:	Examiner: Lindsay, Jr., Walter Lee

For: PECVD SILICON-RICH OXIDE LAYER FOR REDUCED UV CHARGING

**AMENDMENT UNDER 37 C.F.R. § 1.116**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action dated December 30, 2004, pursuant to the provisions of 37 C.F.R. § 1.116.